

# **FIRST INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet 1 of 1

**Complete if Known**

Application Number	Unassigned
Filing Date	December 3, 2003
First Named Inventor	Man WONG et al
Examiner Name	Unassigned
Attorney Docket Number	016660-188

**U.S. PATENT DOCUMENTS**

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
<i>[Signature]</i>	4,533,795		Baumhauer, Jr., et al	08-06-1985
<i>[Signature]</i>	4,558,184		Busch-Vishniac et al	12-10-1985
<i>[Signature]</i>	5,573,679		Mitchell et al	11-12-1996
<i>[Signature]</i>	5,684,324		Bernstein	11-04-1997
<i>[Signature]</i>	6,479,878		Okawa et al	11-12-2002

**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	Translation	
					Yes	No

**NON-PATENT LITERATURE DOCUMENTS**

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<i>[Signature]</i>	Bergqvist, J., et al., "Capacitive Microphone with a Surface Micromachined Backplate Using Electroplating Technology", <i>Journal of Microelectromechanical Systems</i> , Vol. 3, No. 2, June 1994, pp. 69-75, IEEE (1994).
<i>[Signature]</i>	Zou, Q.B., et al, "Design and Fabrication of a Novel Integrated Floating-Electrode-'Electret'-Microphone (FEEM)", <i>Proceedings of the 11th International Workshop on Micro Electro Mechanical Systems</i> , January 1998, pp. 586-590, IEEE (1998).
<i>[Signature]</i>	Murphy, P., et al, "Subminiature Silicon Integrated Electret Condenser Microphone", <i>6th International Symposium on Electrets (ISE 6) Proceedings</i> , 1988, abstract.

4/14/05